



IPW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Yasuaki HAMADA et al.

Group Art Unit: 2818

Application No.: 10/807,357

Examiner: T. NGUYEN

Filed: March 24, 2004

Docket No.: 119223

For: FERROELECTRIC MATERIAL, FERROELCTRIC FILM AND METHOD OF
MANUFACTURING THE SAME, FERROELECTRIC CAPACITOR AND METHOD
OF MANUFACTURING THE SAME, FERROELECTRIC MEMORY, AND
PIEZOELECTRIC DEVICE

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

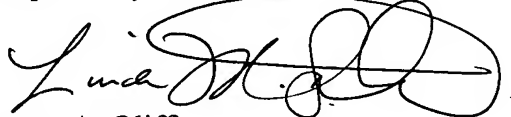
In reply to the February 22, 2006 Restriction Requirement, Applicants provisionally
elect Group I, claims 1-6 and 14-16, with traverse.

It is also respectfully submitted that the subject matter of all claims 1-16 is sufficiently
related that a thorough search for the subject matter of any one Group of claims would
encompass a search for the subject matter of the remaining claims. Thus, it is respectfully
submitted that the search and examination of the entire application could be made without
serious burden. See MPEP §803 in which it is stated that "if the search and examination of an
entire application can be made without serious burden, the examiner must examine it on the
merits, even though it includes claims to independent or distinct inventions" (emphasis
added). It is respectfully submitted that this policy should apply in the present application in

order to avoid unnecessary delay and expense to Applicants and duplicative examination by the Patent Office.

Thus, withdrawal of the Restriction Requirement is respectfully requested.

Respectfully submitted,



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JAO:LMS/hs

Date: March 2, 2006

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